



## ICE300

<b>Component name</b>	<b>ICEC300</b>		
<b>Category (IP/ Reusable)</b>	IP	<b>Component type (HW/Product )</b>	S/W Product
<b>Core</b>	Scheduler	<b>Supporting OS</b>	WindowsXP,2003 Server
<b>Applications / applicable products</b>	Manufacturing		
<b>Market/ industries applicable</b>	semiconductor and PV manufacturing		
<b>Product Description</b>	<p>ICE300 is a fully integrated, object oriented, modular and flexible software framework for automation of semiconductor and PV manufacturing equipments. It enables rapid development and deployment of automation software for different tool configurations.</p> <p>ICE300 has automated various complex equipments (including CVD, PVD, ALD, Etch, Metrology, Ion Implantation, Wet Bench, Furnace, Stocker etc) allowing you to harness the maturity and reliability of an industry proven solution.</p> <p>Built-in compliance to SEMI standards and the rich experience from deployments in fabs around the world helps you to get acceptance of your tools in fabs faster and easier.</p>		
<b>Technical specifications</b>	<ul style="list-style-type: none"> <li>• OS WindowsXP,SP2, ,Windows2003 Server</li> <li>• Memory <ul style="list-style-type: none"> <li>– 2GB RAM</li> </ul> </li> </ul>		
<b>Features /benefits</b>	<p><b>SEMI Compliance</b> ICE300 supports SECS/GEM , 300mm and Interface A standards:E4, E37, E5, E30, E39, E40,E87, E90, E94 ,E116,E120,E125,E132 and E134.It also comes pre-integrated with NeST's ICEConnect300 and other host interface packages.</p> <p><b>Multiple Tool Type Support</b> Supports different tool types including EFEM, EFEM with Vacuum back-end, single and batch hand robots , linked tools , Stocker, Vertical Furnace for SEMI/PV industries.</p> <p><b>Configuration Management</b> Easy to use utilities to handle diverse configuration requirements of equipments, ranging from devices to host connectivity.</p> <p><b>Device Connectivity</b> In-built support for commonly used devices including EFEM platforms, Load Ports</p>		



	<p>(FOUPs, SMIFs, Open Cassettes), Robots, Indexers, Carrier ID readers, Wafer ID readers and Vacuum System components of major vendors.</p> <p><b>Scheduling</b> Supports serial, parallel and concurrent modes of material scheduling for complex equipment configurations. Supports batch and buffer modules. Rule based engine enables throughput optimization.</p> <p><b>User Interface</b> Highly configurable SEMI E95 compliant user interface framework includes screens for Tool Status, Job Management, Manual and Maintenance Operations, User Management and Alarm Management. Other prominent features are multi-language support, custom screen development wizards and third-party screen integration support.</p> <p><b>Integration</b> Provides standard interfaces and Software Development Kit (SDK) combined with exhaustive documentation, for fast and easy integration with different process module controllers.</p> <p><b>Data Analysis</b> Support for data monitoring and visualization of critical equipment and process parameters.</p> <p><b>Simulation</b> Allows testing of equipment behavior for normal scenarios and failure conditions. Enables in-house reliability and endurance testing at OEM premises addressing the problem of tool availability.</p>
<b>Readiness</b>	Ready